

AMENDMENTS TO THE CLAIMS

Please amend the claims as follows.

1. (Currently Amended) A unit for separating gases, which separates each of a plurality of specific gases from a treatment gas containing said specific gases, ~~wherein~~ said unit ~~comprises~~ comprising:
a plurality of columns packed with different fillers, ~~[[and]]~~ wherein by connecting said columns in series~~[[,]]~~ and passing said treatment gas sequentially through said fillers of said plurality of columns, each of said specific gases is separated chromatographically from said treatment gas; and
a plurality of gas discharge lines connected to an outlet of the plurality of columns, each of the plurality of gas discharge lines having a valve,
wherein each of said specific gases that is separated chromatographically from said treatment gas is discharged via a corresponding one of the plurality of gas discharge lines.
2. (Canceled)
3. (Previously Presented) The unit for separating gases according to claim 1, wherein said specific gases are PFC gases discharged from a semiconductor production process, and said treatment gas also contains nitrogen gas.
4. (Previously Presented) The unit for separating gases according to claim 3, wherein said specific gases comprise NF_3 , CF_4 , and C_2F_6 , and said fillers comprise zeolite and activated carbon.
5. (Currently Amended) The unit for separating gases according to claim 4, wherein said zeolite is molecular sieve 13X ~~or an equivalent product.~~

6. (Currently Amended) A unit for separating gases, which separates each of a plurality of specific gases from a treatment gas containing said specific gases, ~~wherein~~ said unit ~~comprises~~ comprising:
- a column packed with a plurality of different fillers, ~~[[and]]~~ wherein by passing said treatment gas through said plurality of fillers inside said column, each of said specific gases is separated chromatographically from said treatment gas; and
a plurality of gas discharge lines connected to an outlet of the column, each of the plurality of gas discharge lines having a valve,
wherein each of said specific gases that is separated chromatographically from said treatment gas is discharged via a corresponding one of the plurality of gas discharge lines.
7. (Previously Presented) The unit for separating gases according to claim 6, wherein said specific gases are PFC gases discharged from a semiconductor production process, and said treatment gas also contains nitrogen gas.
8. (Previously Presented) The unit for separating gases according to claim 7, wherein said specific gases comprise NF_3 , CF_4 , and C_2F_6 , and said fillers comprise zeolite and activated carbon.
9. (Currently Amended) The unit for separating gases according to claim 8, wherein said zeolite is molecular sieve 13X ~~or an equivalent product.~~
10. (New) The unit for separating gas according to claim 1, wherein said specific gases comprise CF_4 and C_2F_6 ,
wherein said fillers comprise zeolite, and
wherein a pore size of the zeolite is larger than a maximum molecular diameter of C_2F_6 .